

CLAIMS

1. A substrate processing module comprising:
a first tank and a second tank that are arranged
5 in a first direction and in which a substrate can be placed;
a first conveyor that moves the substrate in the
first direction;
a second conveyor that moves the substrate in a
second direction intersecting the first direction; and
10 a vertical conveyor that is connected to the
first conveyor and vertically moves the substrate, wherein
a first actuator of the first conveyor and a
second actuator of the second conveyor are respectively
arranged in drive spaces separated from a processing space
15 accessible to the first tank and the second tank, wherein
the first actuator is arranged in a first drive
space, and the second actuator is arranged in a second drive
space, and wherein
the first drive space is provided on a side and
20 below openings of the first tank and the second tank.

2. A substrate processing module comprising,
a first tank and a second tank that are arranged
in a first direction and in which a substrate can be placed;
25 a first conveyor that moves the substrate in the

first direction;

a second conveyor that moves the substrate in a second direction intersecting the first direction; and

a vertical conveyor that is connected to the first conveyor and vertically moves the substrate, wherein

a first actuator of the first conveyor and a second actuator of the second conveyor are respectively arranged in drive spaces separated from a processing space accessible to the first tank and the second tank, wherein

the first actuator is arranged in a first drive space, and the second actuator is arranged in a second drive space, and wherein

the second drive space is provided on a rear side in the first direction with respect to the processing space.

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3. A substrate processing module comprising,

a first tank and a second tank that are arranged in a first direction and in which a substrate can be placed;

a first conveyor that moves the substrate in the first direction;

a second conveyor that moves the substrate in a second direction intersecting the first direction;

a vertical conveyor that is connected to the first conveyor and vertically moves the substrate, wherein

a first actuator of the first conveyor and a

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second actuator of the second conveyor are respectively arranged in drive spaces separated from a processing space accessible to the first tank and the second tank; wherein

the first actuator is arranged in a first drive
5 space, and the second actuator is arranged in a second drive space,

further comprising a rear wall provided behind the processing space, wherein

the second drive space is provided behind the
10 rear wall.

4. The substrate processing module according to claim 3, wherein the rear wall has an exhaust port for exhausting atmosphere of the processing space to the outside.
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5. The substrate processing module according to claim 3 or 4, wherein the second conveyor includes an arm extending forward from the second drive space and passing through an opening provided in the rear wall, and a chuck
20 portion connected to the arm and arranged above the first tank.

6. The substrate processing module according to any one of claims 1 to 5, wherein the second drive space can
25 be connected to an another module.

7. The substrate processing module according to claim 6, wherein

the another module is any one of a loading module,
5 an unloading module, a drying module, and a substrate processing module.

8. The substrate processing module according to any one of claims 1 to 7, wherein the second conveyor further
10 comprises a rotary actuator that rotates a chuck portion for holding the substrate, and wherein

the rotary actuator is arranged in the second drive space.

15 9. The substrate processing module according to any one of claims 1 to 8, wherein a vertical actuator of the vertical conveyor is arranged in the first drive space.

10. The substrate processing module according
20 to any one of claims 1 to 9, wherein each of the first tank and the second tank is any of a liquid chemical tank for processing the substrate with liquid chemical, a cleaning tank for cleaning the substrate, and a one-bath processing tank having a function of processing the substrate with
25 liquid chemical and a function of cleaning the substrate.

11. The substrate processing module according to claim 10, wherein

the first tank is a cleaning tank arranged on a front side in the first direction, and

the second tank is a liquid chemical tank arranged on a rear side in the first direction.

12. A substrate processing apparatus comprising:

the substrate processing module according to any one of claims 1 to 11; and

an another module connected to the substrate processing module in the second direction.